

Events

North Center Ballroom

Tuesday

6:30 AM Training Run
 8 AM-3 PM Registration
 11 AM-7 PM Exhibit Hall Open
 11:15 AM-1:15 PM Exhibitor Sponsored Lunch (Forum)
 7 PM Welcome Reception (Forum)

8:15 Continental Breakfast
 8:45 Welcome to SESH Annual Symposium & Expo and Awards Presentation. *Cox, J.; SESH President*
 9:30 Keynote 1: Semiconductor Industry Forecast and the Future of Nanotechnology. *Feldhan, J.; Semico Research Corporation*
 10:15 Break
 10:30 Keynote 2: Retooling Yourself for the Next EH&S Wave. *Tighe, D.; Bovo-Tighe, Bellevue, WA*
 11:15 Exhibitor Sponsored Lunch in Exhibit Hall
 1:15 Keynote 3: The Semiconductor Industry Association Worker Health Project: An Update. *Fischman, M.; Intel Corporation and Fraust, C.; Semiconductor Industry Association*
 2:00 Keynote 4: Exploring Opportunities to Further Eliminate Potential Equipment Related Exposures. *McIntyre, A.; Environmental and Occupational Risk Management, (EORM, Inc.)*
 2:45 Break in Exhibit Hall
 3:15 Keynote 5: Semiconductor Industry PFC Emissions Estimating and Reduction: Status and Future Directions. *Worth, W.; International SEMATECH and Beu, L.; Laurie Beu Consulting*
 4:00 Keynote 6: Fire Codes 2005 - A Review of the Fire Codes and Standards Applicable to the Semiconductor Industry Today. *Benson, R.; Factory Mutual Global*

Events

Rio Verde/Sonora

Center Ballroom

Wednesday

6:30 AM Training Run
 7:30-8:15 AM Fellows Forum (Executive Board Room)
 8:15-9 AM Exhibitors Meeting (Forum)
 8 AM-2 PM Registration
 9 AM-3:30 PM Exhibit Hall Open

Session 1: Boot Camp: Back to Basics
Moderator: Mark Gordon
 8:00 An Overview of the Semiconductor Manufacturing Process. *Benson, R.; Factory Mutual Global*
 9:30 Poster Session in Exhibit Hall
 10:30 Ergonomic Assessment of Cumulative Trauma Risk. *Kelso, D.; Earth Tech Inc.; San Jose, California*
 11:15 Industrial Hygiene Speak for the Non IH – Applying Strategies and Methods. *Visty, J.; Earth Tech Inc., Colorado Springs, CO*
 Noon Cash & Carry Lunch & Raffle in Exhibit Hall
Session 2: Emerging EHS Technologies & Issues
Moderator: Andy McIntyre
 1:30 The Brave New World of Nanotechnology. *Moffitt, M.; Western Technologies Inc., Phoenix, AZ*
 2:15 Methods & Resources Used to Help Close ESH Data Gaps and New Tools to Screen Novel Semiconductor Chemicals. *Speranza, D. and Kuntz, M.; SEMATECH, Austin, TX.*
 3:00 Ice Cream Break & Raffle in Exhibit Hall
 3:30 Reducing PFC Emissions Through Advances in CVD and Etch Processing. *Johnson, A., Ridgeway, R. and Maroulis, P.; Air Products and Chemicals, Inc., Allentown, PA.*
 4:15 Developing a Climate Change Action Plan. *Higgs, T.; Intel, Chandler, AZ*

Session 3: Leadership Forum
Moderator: Lonnie Schock
 8:00 Thriving in an Era of Scarcity. *Niekerk, G.; Intel Corporation, Chandler, AZ*
 8:45 Integration of an ESH Chapter into the International Technology Roadmap for Semiconductors (ITRS). *Jewett, J.; Intel Corporation, Chandler, AZ*
 9:30 Poster Session in Exhibit Hall
Session 4: EHS Management
Moderator: Bob Bianconi
 10:30 Transitioning Your EMS from ISO 14001:1996 to ISO 14001:2004. *Wilks, L., Esty, P.; Capaccio Environmental Engineering, Inc., Marlborough, MA*
 11:15 Global Care is Smart Business! *Row, R.; SEMI, San Jose, CA*
Session 5: Value-Added EHS
Moderator: Mark Kraus
 Noon Cash & Carry Lunch in Exhibit Hall
 1:30 Identifying and Communicating EHS Value. *MacLean, R.; Competitive Environment, Scottsdale, AZ*
 2:15 Using Business Metrics and Leading Indicators of EHS Performance – Translating EHS into Business Benefit. *Rankin, K.; ERM, Austin, TX*
 3:00 Ice Cream Break & Raffle in Exhibit Hall
Session 6: Chemical & Product Stewardship
Moderator: Jeanne Yturri
 3:30 Around the World in 80 Days with a New Chemical Substance? *Majors, M.; Air Products and Chemicals, Inc., Carlsbad, CA*
 4:15 Intel Corporation's Technology & Development EHS Chemical Approval Process. *Brown, S.; Intel, Hillsboro, OR*

Events

Rio Verde/Sonora

Center Ballroom

Thursday

6:30 AM 5K Run
 7-9 AM Exhibitor Meeting (Forum)
 8-10 AM Registration
 Noon-2 PM Board of Directors Meeting (Prescott Room)
 3:30-4 PM Closing Session

Session 7: Environmental
Moderator: Mike Sherer
 8:00 Common Yet Complex RCRA Issues Facing SESH Environmental Managers: A Discussion of Regulations, Policies and Pointers on Such Topics as Printed Circuit Board Recycling, Management of Contaminated. *von Oppenfeld, R.; TESTLaw Practice Group*
 8:45 Catalytic Decomposition of Ammonia from GaN Processes. *Van Gompel, J.; BOC Edwards, Austin TX*
 9:30 Break
 10:00 Removing Fluoride from Industrial Wastewater Using Hybrid-Membrane Technology. *Peterson, J.; Geomatrix, Scottsdale, AZ and Madole, J.; Nalco, Phoenix, AZ*
 10:45 Chemical Vapor Deposition Process Emission Reduction Using Point-Of-Use Wet Scrubber Technology. *Kempton, C. and Jain, A.; Rogers, Chandler, AZ*
 11:30 Lunch
Session 8: Regulatory/Code Developments
Moderator: Aaron Zude
 1:00 Assessing the Impact of Technology on the Regulatory Process. *Gannod, G.; Koehnemann, H.; Arizona State University, Tempe, AZ and Litchfield, L.; City of Phoenix, AZ.*
 1:45 Fire and Building Codes: One Code or Conflicting Codes? *Hynes, G.; ATS, LLC*
 2:30 Break
Roundtable: Effect of WEEE & RoHS on the Global Electronics Industry Supply Chain
Chair: Brian Sherin, ESHconnect, Inc.
 2:45 PM Opening Remarks. *B. Sherin*
 Semiconductor Equipment Manufacturing. *B. Claes, Lam Research*
 Semiconductor Device Manufacturing. *N. Bolinger, IBM*
 Consumer Electronics/Electronic OEMs. *TBD*

Session 9: Industrial Hygiene
Moderator: Judi Barker
 8:00 Arsenic Regulated Areas – A Reality in the “Clean Semiconductor Industry.” *Rubin, J.; Agilent Technologies, Fort Collins, CO*
 8:45 Health and Nanotechnologies, from Benefits to Hazards. *Proust, N.; TRT-Fr, Orsay, France*
 9:30 Break
Session 10: Occupational Health
Moderator: Molly Doddo
 10:00 Managing Ergonomics as a Process. *Rostykus, W.; Humantech*
 10:45 Personal Empowerment: An Unconventional Concept in Stress Management. *Jackson, C.; Freescale Semiconductor, Tempe, AZ.*
 11:30 Lunch
Session 11: Safety
Moderator: John Blades
 1:00 Intel's EHS New Facilities Equipment Procurement Process (FEPP). *Yurconic, M.; Ronler Acres, Hillsboro, OR*
 1:45 Life Cycle Concerns for a Toxic Gas Monitoring System. *Pugh, J.; Pugh Engineering*
 2:30 Break
 2:45 Arc Flash Safety Practices in the Semiconductor Industry. *Clough, J.; Square D/Schneider Electric, Spokane, WA*
 3:30 Fire Risk Mitigation for Integral IPA Dryers - Using Engineering controls versus Gaseous Fire Suppression. *McDaid, R.; Applied Materials, Santa Clara, CA and Wyman, M.; Koetter Fire Protection, Dallas, TX*